

Date: February 6, 2001

Page 1 of 1

Form PTO-1449

(REV. 8-83)

**U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE**

INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)



ATTY. DOCKET NO.

MEMSC-001XX

APPLICATION NO.

009705096

RECEIVED**MAY 8 - 2001**

APPLICANT:

Yang Zhao et al.

Technology Center 2100

FILING DATE

November 3, 2000

GROUP

Not Assigned

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE*
SM	2,440,189	4/20/48	Zworykin			
SM	2,455,394	12/7/48	Webber			
CM	4,478,077	10/23/84	Bohrer et al.	73	204	
CM	4,542,650	9/24/85	Renken et al.	73	204	
BS	4,581,928	4/15/86	Johnson	73	204	
CS	4,637,253	1/20/87	Sekimura et al.	73	189	
CS	4,651,564	3/24/87	Johnson et al.	73	204	
CS	5,581,034	12/3/96	Dao et al.	73	514.09	
CS	5,719,333	2/17/98	Hosoi et al.	73	514.05	
CS	5,959,208	9/28/99	Muenzel et al.	73	514.32	

FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO

OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER

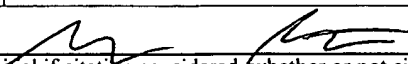
DATE CONSIDERED

2/19/04

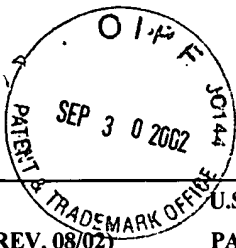
***EXAMINER:** Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: August 30, 2002

Page 1 of 1

U.S. DEPARTMENT OF COMMERCE (REV. 08/02) PATENT AND TRADEMARK OFFICE				ATTY. DOCKET NO. MEMSC-001XX		APPLICATION NO. 09/705,996	
INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)				APPLICANT: Yang Zhao et al.		FILING DATE 11/3/00	
GROUP 2811				RECEIVED SEP 12 2002 TECHNOLOGY CENTER 2800			
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	PUBLICATION/ ISSUE DATE	NAME	CLASS	SUBCLASS	FILING DATE	
5	US6,171,880 B1	1/9/01	Gaitan et al.	438	52		
2	US5,581,034	12/3/96	Dao et al.	73	514.09		
	US						
	US						
	US						
	US						
	US						
FOREIGN PATENT DOCUMENTS							
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO	
OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, etc.)							
on	Freeform Fabrication of Functional Microsolenoids, Electromagnets and Helical Springs Using High-Pressure Laser Chemical Vapor Deposition, K. Williams, et al., pp. 232-237						
sn	Micromachined Accelerometer Based On Convection Heat Transfer, A.M. Leung, et al., 0-7803-4412-X/98, 1998 IEEE, pp. 627-630						
h	Convection-based Accelerometer and Tilt Sensor Implemented in Standard CMOS, Velijko Milanovi, et al, International Mechanical Engineering Conference and Exposition, MEMS Symposia, Anaheim, CA, Nov. 18, 1998.						
EXAMINER				DATE CONSIDERED			
				2/19/04			
*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

* Previously cited and considered on IDS filed 2/9/01



Date: September 24, 2002
Page 1 of 1

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>	ATTY. DOCKET NO. MEMSC-001XX	APPLICATION NO. 09/705,996 RECEIVED OCT - 3 2002 C 2800 MAIL ROOM
	APPLICANT: Yang Zhao et al.	
	FILING DATE 11/3/00	GROUP 2811

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	PUBLICATION/ ISSUE DATE	NAME	CLASS	SUBCLASS	FILING DATE
		US					
		US					
		US					
		US					
		US					
		US					
		US					

FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO

OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, etc.)							
LM		My Work on MEMS, Christian Zincke, 9/27/99, pp. 1-55					

EXAMINER	DATE CONSIDERED 2/19/04
-----------------	--------------------------------

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.